

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

KAJIMOTO et al.

Atty. Ref.: 900-481; Confirmation No.

Appl. No. To be Assigned

Group:

Filed: November 20, 2003

Examiner:

For: METHOD OF MANUFACTURING SILICON WAFER

\* \* \* \* \*

November 20, 2003

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

**PRELIMINARY AMENDMENT**

In order to place the above-identified application in better condition for examination, please amend the application as follows: